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Room temperature epitaxial growth of Zn-doped iron oxide films on c-, a- and r-cut sapphire substrates

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Room temperature epitaxial growth of Zn-doped iron oxide films on c-, a- and r-cut sapphire substrates

Valérie Demange^{1,}, Xavier Portier², Sophie Ollivier¹, Mathieu Pasturel¹, Thierry Roisnel¹, Maryline Guilloux-Viry¹ , Christian Hebert³ , Magdalena Nistor⁴ , Christophe Cachoncinlle⁵ , Eric*

Millon⁵ , Jacques Perriere³

Univ Rennes, CNRS, ISCR – UMR 6226, ScanMAT – UAR 2025, F-35000 Rennes, France

Centre de recherche sur les Ions, les MAtériaux et la Photonique (CIMAP), CEA/UMR CNRS

6252, Normandie Université, ENSICAEN, 14050 Caen Cedex, France

Institut des NanoSciences de Paris (INSP), CNRS UMR 7588 Sorbonne Université, 4 Place Jussieu, Paris Cedex 05 75252, France

National Institute for Lasers, Plasma and Radiation Physics (NILPRP), PO Box MG-36, 077125 Magurele-Bucharest, Romania

GREMI UMR 7344 CNRS-Université d'Orléans, 45067 Orléans Cedex 2, France

KEYWORDS: Oxide thin film. Room-temperature epitaxy. Van der Waals Epitaxy. Graphoepitaxy. Pulsed laser deposition.

> ABSTRACT. The room temperature growth of zinc-doped iron oxide films $(Zn:FeO_x)$ was studied on c-cut, a-cut and r-cut sapphire substrates using the pulsed-laser deposition method. Rutherford backscattering spectrometry, X-ray diffraction analysis, pole figure measurements and transmission electron microscopy were used to determine the nature of the oxide phases (wüstite and/or spinel) present in the films, their precise texture and in-plane epitaxial relationships between films and substrates. On c-cut sapphire, both wüstite and spinel phases were present with a (111) texture. The wüstite phase was mainly found at the film-substrate interface, while the spinel was observed in the upper part of the film. On the a-cut and r-cut substrates, the main phase observed was the wüstite, with a very small spinel contribution. The (111) and (100) wüstite textures were obtained on the a-cut and r-cut substrates, respectively. The in-plane epitaxial relationships between the Zn doped iron oxide phases and the substrates were deduced from transmission electron spectroscopy observations and pole figure measurements. The possible mechanisms of the room temperature epitaxial growth of the oxide films on r-cut and a-cut sapphire substrates are presented and discussed.

Introduction

As it has been largely demonstrated in literature, the epitaxy of oxide thin films on single crystalline substrates usually requires high temperature during the growth $1-5$. However, for a lot of industrial applications based on such epitaxial films, it would be necessary to reduce the growth temperature to avoid atomic interdiffusion between film and substrate, and consequently to significantly reduce the fabrication cost ⁶. In this framework, research activities have been carried out to study room temperature (RT) epitaxial growth of oxide films like NiO 7,8 , Fe₃O₄ 9 , V₂O₃ ¹⁰, CoO and $Co₃O₄$ ¹¹, and other oxides $12-14$. In most of these works, the RT epitaxial oxide films

Crystal Growth & Design

were grown on atomically stepped single crystal sapphire (00l) substrates by using the pulsed-laser deposition (PLD) method $7-14$. Such stepped c-cut sapphire substrates are obtained by a thermal annealing process at high T (1000 $^{\circ}$ C) for a few hours in air ^{15,16}. The surface steps play the role of nucleation centers for the epitaxial growth of the film. On the other hand, PLD is used for the film growth at RT owing to one of the specificities of this method, i.e. the high kinetic energy of the species emitted by the target during laser irradiation. Indeed, such a high kinetic energy (about a few 10th eV) ¹⁷ allows a high surface mobility for the species that leads to the formation of crystalline material at relatively low temperature ^{18,19}.

In addition to the RT epitaxial growth of oxide films on c-cut (00l oriented) sapphire substrates, some other papers report the RT epitaxy of oxide films on single crystal substrates like MgO 20 , SrTiO₃ 21 , bare Si $^{22-24}$ or Si covered by a buffer layer 25 . However, some other single crystal substrates like a-cut ((110) oriented) and r-cut ((102) oriented) sapphire substrates are currently used for the epitaxial growth of various oxide films $26-31$ with a view of specific applications $32-34$. To our knowledge, the RT epitaxy of oxide films on such a-cut and r-cut sapphire substrates has never been reported.

In this frame, we have studied the growth by PLD at RT of Zn-doped iron oxide on a-cut and r-cut sapphire substrates. For comparison purpose, ZFO films were also grown on a c-cut substrate, but more complex results obtained with this substrate will be published later in a forthcoming paper. Owing to the experimental PLD conditions used, two iron oxide-based phases are obtained: the Zn-doped wüstite phase $Zn:FeO$ that will be noted " ZFO_w " in the following and the Zn-doped Zn:Fe₃O₄ spinel magnetite phase (noted "ZFO_s"). More precisely, $Zn_{1-x}Fe_xO$ films with $(0 \le x \le 1)$ can be grown by PLD: following previous work³⁵, the Zn:Fe₃O₄ phase is obtained for 0.65 $\leq x \leq 1$. We have chosen a Zn concentration fixed at around 25% at. (x = 0.75) to avoid the

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formation of the wurtzite phase. In addition, the presence of Zn in the iron oxide phases should promote the growth the wustite phase even at low temperature ($T < 500^{\circ}$ C) as evidenced by Sano et al. ³⁶. We present here a detailed structural study of these phases deposited at RT on the various sapphire substrates: growth, textures and epitaxial relationships between these compounds and the different substrates are discussed. Such films could be of interest due to their magnetic properties since wüstite-based films are expected to be antiferromagnetic while magnetite-based films should be ferrimagnetic. These properties would permit the development of magnetite-based storage or spintronics devices $37,38$, while wüstite could be used as a transparent p-type conductors 39 or for magnetoresistance enhancement ⁴⁰. However, these interesting physical properties are not the subject of this paper which is devoted to the detailed study of the structural properties of these films.

In our work, in contrary to the common high T annealing of the substrates before the film growth, all the c-, a- and r-cut sapphire substrates were not submitted to a thermal treatment at high T before the growth. Despite this point, we obtained the epitaxial growth at RT of the Zndoped wüstite (ZFOw, space group *Fm*-3*m*) and/or spinel (ZFO^s , *Fd*-3*m*) phases in the films. Different textures were obtained for these phases on the following type of substrates, i.e. (111) for the c-cut and a-cut sapphire, and (00l) for the r-cut one. Well-defined epitaxial relationships were found between films and substrates, and they have been described in the frame of the "domain matching epitaxy" (DME) 41–44. The different textures observed depending on the substrates, could be explained either by (i) the graphoepitaxy related to the presence of steps and terraces on the ccut and a-cut substrates⁴⁴⁻⁴⁶, (ii) a "quasi van der Waals epitaxy" related to the polar nature of the c-cut and a-cut substrate plane and/or film plane 47–50, and (iii) an epitaxy related to a low lattice mismatch between the film and substrate in the case of the r-cut sapphire substrate.

Experimental section

The Zn-doped iron oxide films were grown by PLD onto c-cut, a-cut and r-cut sapphire substrates at RT in vacuum. The substrates furnished by CrysTec GmbH were not annealed at high T before the growth. A frequency quadrupled Nd-doped yttrium aluminum garnet (Nd:YAG) laser (266 nm, τ = 7 ns) was used to ablate a Zn:Fe₃O₄ (Zn_{0.85}Fe_{2.15}O₄) target in the experimental set up already described elsewhere . The PLD growth from a Zn:Fe₃O₄ target can lead to the formation of nanocomposite films $52,53$, i.e. with the presence of the wüstite (Zn:FeO) and spinel (Zn:Fe₃O₄). In contrary to the spinel phase, which has been epitaxially grown at $RT⁹$, the wüstite phase has never been obtained in these conditions. In our work, we have tried to favor the growth conditions for the epitaxy of the wustite phase at RT. Indeed, the difference in oxygen composition between the wüstite, $[O]/[Fe] = 1.1$, and the spinel, $[O]/[Fe] = 1.33$, means that the film must be grown under a low oxygen pressure. PLD allows oxygen incorporation in the oxide films to be controlled $54-58$. On one hand, the films on a-cut and r-cut substrates were thus grown under reducing conditions (residual vacuum: 2×10^{-7} mbar), i.e. a priori the ideal conditions for the formation of the wustite phase. On the other hand, the ZFO film on c-cut substrate was grown at 7 10-6 mbar leading to the presence of both wüstite and spinel phase.

Atomic force microscopy (AFM) was used to study the surface topography of the bare substrates before the growth, using an AFM NT-MDT Ntegra instrument.

Rutherford backscattering spectrometry (RBS) using the 2.5 MeV ion accelerator (SAFIR) of the Sorbonne Université, allowed the film thickness and in-depth distribution of the elements to be determined. The spectra, not presented here, show that the Zn-doped iron oxide films are only constituted by Fe, Zn and O atoms, without the presence of any impurities. The precise

concentration profile of the Zn, Fe and O elements has been obtained from the simulation of the RBS spectra by use of the RUMP simulation program and has allowed to deduce the [O]/[Fe] ratio in the films.

X-ray diffraction (XRD) has been performed on a Bruker D8 Advance θ -2 θ diffractometer in modified Bragg-Brentano geometry, working with monochromatized Cu K α 1 radiation (λ = 1.5406 Å) and equipped with a LynxEye detector. The sample was rotated at a speed of 30 rpm during measurement. Le Bail profile refinement using the Fullprof software ⁵⁹ of the XRD patterns of ZFO films grown on a-cut and r-cut sapphires enabled to precise unambiguously whether ZFO_w and ZFO_s phases are both present and to estimate the cell parameters of these phases. For these refinements, the "zero"-shifts due to the sample positioning were first determined from the *2* shifts of the substrate Bragg peaks, and then fixed to enable the refinement of the cell parameters of the iron oxide phases. The texture of the films and the in-plane relationships with the substrate were investigated by pole figure measurements with the help of a Bruker D8 Discover diffractometer (Cu Kα1,2 radiation).

For transmission electron microscopy (TEM) observations, thin foils were thinned down to electron transparency by a focused ion beam (FIB) setup (Dual-beam FEI Helios nanolab 660) with an electron imaging resolution of 0.6 nm at 15 kV (Field emission gun (FEG)) and a FIB resolution of 2.54 nm at 30 kV. TEM experiments were performed using a double corrected cold FEG JEOL ARM 200F microscope, operated at 200 kV and equipped with a post column GATAN QUANTUM ER electron energy loss spectrometer (EELS). This microscope had also a scanning setup (STEM mode with dark and bright field detectors) allowing the electron beam to be monitored with a spatial resolution of about 0.078 nm. Altogether, STEM EELS experiments were

then possible in order to obtain EELS spectra for a nanometer region, EELS profiles or even EELS mapping. All digitized images and spectral data were processed using the commercial Digitalmicrograph (GMS2) software from GATAN.

Results

Before the RT growth of ZFO films on the single crystal substrates, AFM images of the surface of these substrates were registered. Figure 1 shows the surface morphology of the c-cut (Fig. 1(a)), a-cut (Fig. 1(b)) and r-cut (Fig. 1(c)) sapphire substrates as furnished by CrysTec GmbH.

Both c-cut and a-cut sapphire substrates show not very well defined and very narrow steps without terraces, while the surface of the r-cut sapphire does not show any steps or terraces but only a few spikes. This work mainly aimed at checking the possible RT epitaxy of ZFO films on a- and r-cut sapphire substrates. First, we have looked at the possible RT epitaxy of ZFO on a ccut substrate. Indeed, the RT epitaxy of Zn $(25\%at.)$ doped Fe₃O₄ has not been previously reported on c-cut substrate. Therefore, the PLD growth of such a film on a c-cut substrate at RT under a 7x10-6 mbar oxygen pressure has been studied. Figure 2 reports the corresponding XRD pattern of such film and shows first, a broad peak at about 18° related to the (111) spinel phase with refined cell parameter $a_s = 0.8529 \pm 0.0005$ nm, i.e. higher than the expected theoretical value for undoped Fe3O4 (*a* = 0.83905 nm, *Fd*-3*m*). Secondly, a broad asymmetric peak around 36° corresponding to the superimposition of 222 spinel and the 111 wüstite Bragg reflections is observed. Despite the low intensity of the 111 ZFO_w peak, the cell parameter is around $a_w = 0.43217 \pm 0.0005$ nm, a value slightly higher than for the undoped FeO phase $(a = 0.4307 \text{ nm}, Fm-3m)$ (Table 1).

Table 1. Composition determined by RBS and crystallographic features determined by XRD of ZFO films grown at RT on c-cut, a-cut and r-cut sapphires (W: wüstite, S: spinel). The values of [O]/[Fe] does not consider oxygen bound to zinc and are only related to oxygen associated to iron.

TEM analysis was led to precisely investigate the epitaxial growth of the ZFO film on ccut sapphire substrate. Figure 3(a) shows a typical high resolution electron microscopy (HREM) image of a cross section of the film. The orientation of the sample is such that the electron beam is parallel to the [210] direction of Al_2O_3 sapphire (visible at the bottom of the image) and thus parallel to the film/substrate interface. In the upper region of the film, one can notice distinctly that we are dealing with a columnar growth with column widths of a few tens of nanometers whereas the bottom of the film appears more "uniform" without visible boundaries over a thickness of about 15 nm by contrast with the upper region.

By extracting and enlarging smaller regions from these parts of the film (shown in Fig. 3(b) for the rough images and 3(c) for the corresponding filtered images), an analysis of the lattice

fringes through Fast Fourier Transforms (FFTs) allows establishing the structural characteristics and then the corresponding phases. The FFTs presented in Fig. 3(d) reveal that the bottom part of the film is consistent with a face centered cubic structure along a [-101] direction with a lattice parameter of 0.43 nm. This agrees with the wüstite phase (FeO) doped with Zn (confirmed by chemical analyses, not shown). The corresponding orientation relationships between sapphire and ZFO_w are the following:

 (111) ZFO_w // (003) Al₂O₃

 $[-101]$ ZFO_w // $[210]$ Al₂O₃

As far as the upper region is concerned, the FFT of the enlarged image shows also a face centered cubic structure but with a lattice parameter close to that of the spinel phase $Fe₃O₄$. Zn is also present in the chemical composition of the compound and the orientation relationships between wüstite and magnetite are:

> (111) ZFO_w // (111) ZFO_s $[-101]$ ZFO_w // $[10-1]$ ZFO_s

To confirm the presence of both phases, a spectroscopic analysis using EELS method has been used. In Fig. 3(a), two spots are indicating the two pointed regions from which one obtained the EELS spectra presented in Fig. 4.

These spectra correspond to the L_2 and L_3 thresholds of Fe whose positions are indicative of the valence sate of Fe. A 1 eV displacement of the L_3 peak towards lower energies for the bottom of the film is clearly meaning a decrease in the valence state of Fe and then consistent with the

presence of the wüstite phase at the bottom of the film. Similar shift for these compounds has been reported in previous works ⁶⁰. The presence of the wüstite phase is also in agreement with the [O]/[Fe] ratio deduced from RBS measurements, the obtained values being between 1.13 and 1.19 (Table 1).

The XRD *θ*-*2θ* patterns recorded on the ZFO films grown on the a- and r-cut substrates are presented in Fig. 5. The data regarding the lattice parameters and the full width at half maximum (FWHM) of the rocking curves are summarized in Table 1. The XRD pattern (Fig. 5(a)) recorded for the film grown on the a-cut sapphire shows the presence of the 111 wüstite reflection at about $2\theta = 35.75^{\circ}$. The 111 and 222 spinel peaks which would appear at 18° and 36.6° respectively, are not observed in this pattern. Profile refinement using a single FeO phase leads to satisfying modelisation of the observed peak and suggests that the film is constituted of a pure wüstite phase.

In Fig. 5(b), the XRD pattern corresponding to the film grown on the r-cut substrate shows a wide peak at about 41.75°. Best profile refinement is obtained by considering simultaneous presence of 200 and 400 Bragg reflections of ZFO_w and ZFO_s phases, respectively, showing a significant texture of these films. Due to the limited number of observed diffraction peaks, it is not possible to retrieve the proportional distribution of each phase from the refinement.

For the ZFO films grown on the a-cut substrate, the rocking curve (not shown here) of the respective 111 reflection peaks is rather narrow, i.e. 1.9°, taking into account the RT growth. On the contrary, for the ZFO film grown on the r-cut substrate, the value of the rocking curve of the 002 ZFO_w reflection was much more important, i.e. 4.7°. In this latter case, the crystalline quality of the film is poorer. It must be noticed that in the case of the epitaxial growth of various oxide films on r-cut sapphire substrate, the surface plane of the oxide film was tilted with respect to the

Crystal Growth & Design

(102) plane of sapphire. This phenomenon was observed for instance in the epitaxial growth of ZnO ⁶¹, CeO₂⁶², MgO ^{63,64} or Fe₃O₄⁶⁵. The tilt can be important, for example the (100) MgO may epitaxially grow on (102) Al_2O_3 with a tilt up to 5 or 6°, depending upon the growth temperature. From such results, it was concluded that the surface state of r-plane sapphire is an important factor leading to the tilted growth of the epilayer 63-65. In our present case, it is not surprising that the epitaxial growth of ZFO on r-plane Al_2O_3 occurs at RT with a tilt of about 4.7°.

Figure 6(a) shows the results of the epitaxial relationships study between the wüstite phase and the a-cut substrate. The phi-scan performed on the $\{200\}$ planes of the ZFO_w phase (20 = 42.391°; ψ = 56.22°) shows 6 peaks separated by 60°. In addition, phi-scan of the {104} planes of sapphire ($2\theta = 35.14^{\circ}$; $\psi = 57.55^{\circ}$) was also performed to deduce the crystalline orientations of the film with respect to the substrate. It shows 2 peaks separated by 180° and located at about 6.2° of the closest peak of the film. Figure 6(b) shows the pole figure recorded with the 200 ZFO_w reflection ($2\theta = 42.39^{\circ}$) for the same film grown on the a-cut substrate. This figure presents 6 well defined poles at ψ equal to 56.22°, in agreement with the phi-scan in Fig. 6(a). Some other poles from the substrate are also observed at: i) $\psi = 29^\circ$ corresponding to the 113 Al₂O₃ reflection (owing to the angle between (110) and (113) planes (28.78°) and the Bragg reflection of (113) plane: 2θ $= 43.36^{\circ}$) and ii) $\psi = 64^{\circ}$ corresponding to the -123 Al₂O₃ reflection (angle between (110) and (113) planes = 64.01° and 2θ (-123) = 43.36°).

From the azimuthal positions of the respective peak/poles of ZFO_w and Al_2O_3 , it is demonstrated that the epitaxial relationships on the a-cut sapphire substrate correspond to the superposition of the hexagons of the (111) ZFO_w plane on the rectangular lattice of the a-cut sapphire, with a slight disorientation between the two lattices, as shown in Fig. 7(a). Given this pattern, no match can be observed between the two lattices.

Actually, the explanation of the epitaxial growth of ZFO_w on Al_2O_3 is in the frame of the domain matching epitaxy (DME), with *m* lattice units of the film matching with *p* lattice units of the substrate 64 , as shown in figure 7(b). This figure presents the in-plane lattices of ZFO_w and sapphire which are superimposed considering the 6.2° of rotation between the (2-20) plane of ZFO_W and the (1-1-4) plane of the sapphire. The interception of these planes with the in-plane lattices (traces) corresponds to the traces of the (200) plane of ZFO_W and the (10-4) plane of the sapphire chosen to carry out the phi-scans measurement. It can be seen in figure 7(b) that there is a coincidence of sites between the two lattices leading to a matching domain forming a parallelogram. Since the Bravais lattice of the sapphire is hexagonal, it is not possible to easily determine the directions which correspond to the sides of this parallelogram. We have therefore described the epitaxial relationships between the two lattices by instead considering rather the planes which form the parallelogram, as follows:

Out-of-plane: (111) ZFO_w // (110) Al_2O_3

In-plane (I) (11-2) ZFO_{W} // (1-12) Al_2O_3

In-plane (II) (-871) ZFO_W // (1-1-4) Al₂O₃

In-plane (III) $(3-1-2)$ ZFO_W // $(1-1-1)$ Al₂O₃

Only the shortest side of the parallelogram corresponds to a perfect fit of m lattice units (*m* $=$ 5 for ZFO_W and $p = 1$ for Al₂O₃). Therefore, lattice mismatches are determined by considering

Page 13 of 40

 the interatomic distances shown in figure 7(c). It appears that these distances are very close between the two lattices, corresponding to low mismatch values (cf. Table 2).

Substrate	Epitaxial relationships	Domain matching relationships		Lattice mismatch	Domai n size
		m	\boldsymbol{p}	δ (%)	\bf{D} (nm)
a-cut	$(11-2)$ ZFO _W // $(1-12)$ Al ₂ O ₃	5	1	1.2	1.52
	(-871) ZFO _W // (1-1-4) Al ₂ O ₃			-1.38	2.12
	$(3-1-2)$ ZFO _W // $(1-1-1)$ Al ₂ O ₃			-2.21	2.78
r-cut	$[100]$ ZFO _w // $[010]$ Al ₂ O ₃	11	10	-0.06	4.7
	$[010]$ ZFO _w // $[2-1-1]$ Al ₂ O ₃	6	5	-1.28	2.6

Table 2. Epitaxial relationships of Zn:FeO wüstite films grown at RT on a-cut and r-cut sapphires.

Figure 8(a) displays the phi-scans of the ZFO film grown on r-cut sapphire recorded by selecting the $\{111\}$ planes. It shows 4 peaks separated by 90° and located for the closest one at about 45.5° of the (006) substrate plane. The corresponding pole figure is shown in Fig. 8(b). Similarly, the pole figure (Fig. 8(b)) for the ZFO film grown on the r-plane Al_2O_3 was also recorded. From the azimuthal positions of the peaks/poles, the following epitaxial relationships were deduced:

 (100) ZFO_w // (102) Al₂O₃

- (I) $[100] ZFO_w$ // $[010] Al_2O_3$
- (II) $[010] ZFO_w$ // $[2-1-1] Al_2O_3$

Such orientation relationships correspond to the superposition of the square lattice plane (001) of ZFO_w on the rectangular lattice of the (102) plane of Al_2O_3 substrate as shown in Fig. 9(a).

These two relationships lead in both case to rather large lattice mismatch, 9% for (I) and 15.6% for (II), respectively. Regarding the DME, as indicated in Table 2, a coincidence for relation (I) is obtained with 10 substrate units and 11 film units giving a -0.06% lattice mismatch. For the relation (II) the coincidence is realized with 5 substrate units and 6 film units with a -1.28% mismatch (Fig. 9(b)).

Discussion

In the previous works reported on the RT epitaxy of oxide films, results were usually obtained on c-cut sapphire substrates, and two main points play a role on this epitaxy. The first is the presence of steps and terraces on the c-cut surface. These steps and terraces are due to a miscut and $/$ or a high T annealing of the c-cut sapphire substrate $15,16$, which will play the role of nucleation centers for the epitaxial growth. This kind of growth corresponds to the graphoepitaxy . The second point is the fact that the c-cut sapphire plane is polar, i.e. either a pure oxygen plane or a pure Al plane. In the case of the cubic oxides (NiO, Co_3O_4 , Fe₃O₄, ...), epitaxially grown at RT or at high T on c-cut substrate, the observed texture is (111) , i.e. a plane which is also a polar plane ⁴⁵. The epitaxial growth concerns thus two polar planes, and this situation is very similar to the quasi van der Waals epitaxy 48,49 where there is only very little or no chemical bonding between the atoms of the film and substrate. Indeed, the stability and the epitaxy of the film-substrate interface are related to the weak electrostatic interaction between the two polar planes ⁵⁰.

Crystal Growth & Design

In the case of the ZFO epitaxial growth on c-cut substrate, the epitaxial relationships are the same as those observed in the case of the growth of ZFO on this substrate at elevated temperature ⁵², i.e. the growth occurs with a "30 $^{\circ}$ rotation" of the hexagons of the (111) ZFO plane on the hexagon of the (002) sapphire plane**.** It should be reminded that, in this work, the substrate was not thermally treated, so the AFM image shows presence of steps, but however much less defined than the ones obtained with a high thermal treatment at 1000°C. Moreover, after the film growth, the AFM images (not shown) does not show any steps or terraces which is rather different from the results commonly reported in which steps and terraces are present at the surface of the oxide films grown at RT on c-cut substrates annealed at high temperature before the growth. In our case, polar nature of the c-cut sapphire substrate and of the (111) plane of the Zn-doped iron oxide may lead to an electrostatic interaction at this interface. Therefore, it seems reasonable to conclude that both the graphoepitaxy and the quasi van der Waals epitaxy are at the origin of the RT epitaxy of ZFO on c-cut sapphire substrate. Concerning the film grown on the a-cut substrate, it must be noticed that this substrate is also either a pure cationic or a pure oxygen one. Our results show that the RT epitaxy of the wüstite phase is based on the (111) ZFO_w plane, despite the fact that the a-cut substrate and the (111) ZFO_w present very different atomic configuration, i.e. a symmetry mismatch between the substrate (2-fold) and the (111) ZFO_w film (3-fold).

An interesting point which can be noticed is that such epitaxial relationship (111) ZFO_w // (110) Al₂O₃ corresponds to an epitaxy of a hexagon on a rectangle with different symmetries for these two planes. One can ask thus why an epitaxy with a square (ZFO_W) on a rectangle (r-cut $A₁₂O₃$) is not observed while the square and rectangular configurations would be more relevant. Concerning the DME, it is possible to obtain the lattice mismatch δ and domain matching epitaxy

D in terms of the epitaxial relationships with (001) ZFO_w // (110) Al_2O_3 . The calculated values of δ and D are the following:

[100] ZFO_w // [001] Al_2O_3 m = 3 p = 1 δ = 0.02 % D = 1.3 nm [001] ZFO_w // [1-10] Al_2O_3 m = 19 p = 10 δ = 0.13 % D = 8.3 nm

The comparison of these values with those given in Table 2 for the (111) ZFO_w // (110) $A₁₂O₃$ indicates that the epitaxy of the square (001) ZFO_w on the rectangular (110) $A₁₂O₃$ is better in terms of DME. The reason why this epitaxy is not observed is certainly related to the fact that the (100) ZFO_w plane is not a polar plane, i.e. O and Fe are present in this plane. It can be concluded that the van der Waals epitaxy based on the electrostatic interaction between the $(111) ZFO_w$ and the (110) Al₂O₃ is preferred to the simple "square on rectangular" epitaxy.

It follows thus that the (111) ZFO_w texture could be explained in the frame of an electrostatic interaction due to the "quasi Van der Waals epitaxy". Indeed, the (111) plane in the wüstite (FCC structure) is a polar plane, and the a-cut sapphire plane is also a polar plane. An electrostatic interaction between these two polar planes is thus envisaged in a similar way to the quasi van der Waals epitaxy.

For the ZFO film grown on the r-cut substrate, the (100) wüstite texture is observed. This is rather surprising since this situation is *a priori* similar to the a-cut substrate case. Indeed, the rcut plane is either a pure oxygen plane or a pure cationic plane, and it presents a rectangular atomic configuration. As for the a-cut surface plane, the (111) wüstite texture could be expected, but the (100) wüstite texture is observed. This means that both the graphoepitaxy and/or van der Waals epitaxy cannot be envisaged to explain the epitaxial growth of ZFO on the r-cut sapphire substrate.

Crystal Growth & Design

We mentioned above the specific problem of the tilt in the epitaxy on r-cut substrate, but another parameter is the growth temperature, which plays an important role in the epitaxial growth of oxide films on the r-cut substrate. For example in the case of $CeO₂$ films grown on a r-cut substrate thermally treated at high T (1000°C), steps and terraces are formed at the surface and a pure (100) $CeO₂$ texture is observed for example 28,67,68 . Moreover, the steps are formed along the [010] direction of the r-cut substrate, which is one of the in-plane directions of the epitaxy. On the contrary, when the r-cut substrate is not thermally treated at high temperature, steps and terraces are not formed, and both (111) and (100) $CeO₂$ textures are observed ^{28,67,68}. Further studies on $CeO₂$ films on r-cut substrates have shown that the growth temperature plays an important role on the film texture ⁶⁹. Indeed, the texture of CeO₂ films changed from (001) at 150°C to a mixed (001) and (111) textures at 300° C, and finally to pure (111) for increasing temperatures ⁴. In our work, the presence of steps and terraces on the r-cut substrate (Fig. $1(c)$) is not clearly evidenced from the AFM images, and furthermore only the (100) ZFO_w texture is observed. Moreover, our films are grown at RT, and we can thus assume that the (100) ZFO_w texture is due to the low growth temperature of the film in a similar way to the case of the $CeO₂$ film grown on r-cut sapphire substrates ⁶⁹.

Conclusion

Using a $Zn:FeO_x$ target, the wüstite (Zn:FeO) and/or spinel (Zn:Fe₃O₄) phases were obtained on c-cut, a-cut and r-cut sapphire single crystal substrates by pulsed laser deposition at room temperature. Depending upon substrates, the two textures, (111) or (100), may be obtained, and poles figures showed the RT epitaxy of the films on all substrates. The possible origin of these distinct textures and epitaxial relationships has been discussed according to both the « graphoepitaxy » and the « quasi van der Waals epitaxy » for the films grown on the c-cut and a-

cut substrates. For the film grown on the r-cut, the (100) texture is obtained as it has been observed in other cases. An important point in the RT epitaxy of the ZFO films is the high kinetic energy of the species emitted by the target during the laser ablation. Such a high kinetic energy of these species will give them the possibility to move on the substrate on sufficient long distances to find their site in the growth of the crystal structure. Finally, this work shows that the RT epitaxy of the oxide films is quite possible on various sapphire substrates (c-cut, a-cut and r-cut), and this opens the way to the PLD growth of oxide films on substrates like MgO, $MgAl₂O₄$ or others at RT.

AUTHOR INFORMATION

Corresponding Author

*Information for the author to whom correspondence should be addressed: Dr. Valerie Demange.

Valerie.demange@univ-rennes.fr

Author Contributions

The manuscript was written through contributions of all authors. All authors have given approval to the final version of the manuscript. VD performed the XRD characterizations and LeBail refinement, analyzed and interpreted the corresponding data and drafted the article. XP performed the TEM and EELS measurements, analyzed and interpreted the corresponding data and drafted the article. SO performed the AFM measurements. MP and TR performed LeBail refinement,

analyzed and interpreted the corresponding data. CH and MN synthetized PLD films, performed RBS measurements, analyzed and interpreted the corresponding data. MGV revised the manuscript. CC and EM analyzed and interpreted the data and drafted the article. JP conceived and designed the project, analyzed and interpreted the data and drafted the article.

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ABBREVIATIONS

RT, room temperature; PLD, pulsed-laser deposition; ZFO_w, wüstite phase Zn:FeO; ZFO_s, Zndoped $Zn:Fe₃O₄$ spinel magnetite phase; Nd:YAG, Nd-doped yttrium aluminum garnet; AFM, atomic force microscopy; RBS, Rutherford backscattering spectrometry; XRD, X-ray diffraction;

TEM, transmission electron microscopy; FIB, focused ion beam; FEG, Field emission gun; EELS, electron energy loss spectrometer; STEM, scanning transmission electron microscopy; HREM, high resolution electron microscopy; FFT, Fast Fourier Transform; FWHM, full width at half maximum; DME, domain matching epitaxy.

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Room temperature epitaxial growth of Zn-doped iron oxide films on c-, a- and r-cut sapphire

substrates

Valérie Demange, Xavier Portier, Sophie Ollivier, Mathieu Pasturel, Thierry Roisnel, Maryline Guilloux-Viry, Christian Hebert, Magdalena Nistor, Christophe Cachoncinlle, Eric Millon, Jacques Perrière

Synopsis: Room-temperature epitaxial growth of Zn doped FeO wüstite thin films on c-cut, a-cut and r-cut sapphire substrates

Figure 1. AFM image of c-cut, a-cut and r-cut sapphire substrates without any annealing before the PLD growth.

181x47mm (300 x 300 DPI)

Figure 2. Experimental θ-2θ XRD pattern (black symbols) of the ZFO film grown on c-cut sapphire substrate showing a peak at about 18° corresponding to the 111 Bragg reflection of the spinel phase and a broad peak around 36° corresponding to the 111 reflection of wüstite and the 222 reflection of spinel phases, respectively. This pattern has been refined using the Le Bail method and calculated and difference patterns are shown as red and blue lines, respectively.

288x201mm (300 x 300 DPI)

ACS Paragon Plus Environment

Figure 3. a) HREM image of a cross section of a ZFO film on c-cut sapphire substrate showing a thin region of ZFOW at the bottom of the film; b) and c) are enlarged regions of the different parts of the film and the Al2O3 sapphire substrate corresponding to rough and filtered images respectively; d) FFTs of the previous mentioned images leading to the identification of the structures.

385x229mm (300 x 300 DPI)

About 1 eV shift

of the L_3 peak for

lower region

Top of the film

Bottom of the film

 L_2

720

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 L_3

705

141x90mm (330 x 330 DPI)

Energy loss (eV)

 710

Figure 7: a) Scheme of the epitaxy of (111) ZFO_W grown on the a-cut sapphire substrate, determined by phi-scans measurement. b) Scheme of the domain matching epitaxy of (111) ZFO_W grown on the a-cut sapphire substrate, showing the site coincidences between the two lattices. The 6.2° rotation between the $(2-20)$ ZFO_W plane and the $(1-1-4)$ sapphire plane highlighted in the phi-scans is shown. c) Interatomic distances of the two lattices reported on the scheme.

254x93mm (96 x 96 DPI)

-
-

 \mathbf{b}

 $6ZFO_W$ u.c. on 5 Al₂O₃ u.c.

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11 ZFO_W u.c. on 10 Al₂O₃ u.c.

 ϵ

 $a)$

[211] Al₂O₃ 010] ZFO_W

> \bullet Fe O Al

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 \bullet

 \bullet

[010] Al_2O_3 [100] ZFO_W

309x138mm (150 x 150 DPI)